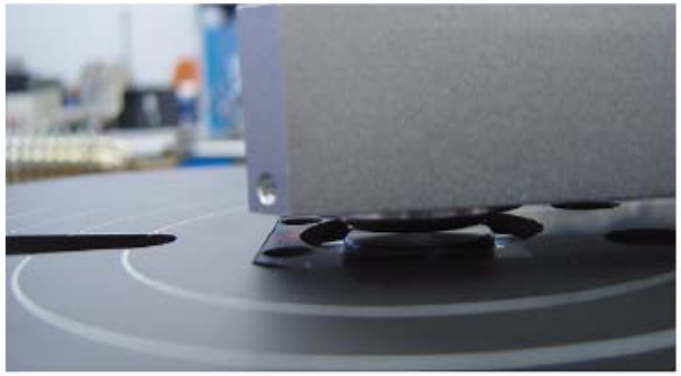
EC-80 Non-contact sheet resistance /resistivity measurement instrument



Selling Points

Easy operation and compact design
Auto-measurement start by inserting a wafer under the probe
Easy set up to measurement condition by JOG dial
5 types of model for each measuring range

Details

Applications

Semiconductor materials, Solar-cell materials (Silicon, Polysilicon, SiC etc)
New materials, functional materials
(Carbon nanotube, DLC, graphene, Ag nanowire etc)
Conductive thin film (Metal, ITO etc)
Silicon-related epitaxial materials, Ion-implantation sample
Chemical compound semiconductor (GaAs Epi, GaN Epi, InP, Ga etc)
Others (*Please contact us for details)

Sample sizes

~8 inch, ~156x156mm

Measuring range

[R] 1m ~ 200 Ω·cm [RS] 10m ~ 3,000 Ω/sq
* The range is separated from each Low, Middle, High and S-High probe type.
*Please refer the measurement range for each probe type as below;

①Low : 0.01~0.5Ω/sq (0.001~0.05Ω·cm)
②Middle : 0.5~10Ω/sq (0.05~0.5Ω·cm)
③High : 10~1000Ω/sq (0.5~60Ω·cm)
④S-High : 1000~3000Ω/sq (60~200Ω·cm)